



Components, Packaging, and Manufacturing Technology Society Newsletter



THE GLOBAL SOCIETY FOR MICROELECTRONICS SYSTEMS PACKAGING

VOL. 35 NO. 3, FALL 2012, ISSN 1077-2999

cpmt.ieee.org

More Value From Your CPMT Membership

Your IEEE Components, Packaging and Manufacturing Technology (CPMT) Society membership will give you more value than ever in the coming year.

When you renew for 2013, your CPMT membership (US\$15; Students US\$8) will include an electronic subscription to *IEEE Transactions on Components, Packaging and Manufacturing Technology*, published monthly.

You can also add a print subscription to *IEEE Transactions on Components, Packaging and Manufacturing Technology*.

If you are interested in adding a print subscription to *IEEE Transactions on Components, Packaging and Manufacturing Technology* for US\$25 (\$13 for students) as you renew, sign in

with your IEEE Account. Once signed in, a page will present that includes your contact information, and all 2012 memberships and subscriptions. On this page is the Membership Media Options section. In that section, click "edit" under IEEE Components, Packaging and Manufacturing Technology Society Membership and a box will pop up. Simply click the checkboxes to opt in and opt out of possible subscription options, and click "Save" to continue.

If you plan to renew your membership by mailing back your printed invoice, and wish to receive the print version of *IEEE Transactions on Components, Packaging and Manufacturing Technology*, simply write "*IEEE Transactions on Components, Packaging and Manufacturing Technology Print*" on the printed invoice, and add US\$25 (US\$13 for students) to the total bill.

NEWSLETTER SUBMISSION DEADLINES:

1 December 2012 for Winter issue

1 February 2013 for Spring issue

1 May 2013 for Summer issue

1 August 2013 for Fall issue

Submit all material to nltr-input@cpmt.org

CPMT Officers

President:	S-W. Ricky Lee	rickylee@ieee.org
VP (Technical):	Jie Xue	jixue@cisco.com
VP (Conferences):	Jean Trehwella	jeanmh@us.ibm.com
VP (Publications):	R. Wayne Johnson	johnsr7@auburn.edu
VP (Education):	Kitty Pearsall	kittyp@us.ibm.com
VP (Finance):	Thomas G. Reynolds III	t.reynolds@ieee.org
Sr. Past Pres.:	William T. Chen	William.Chen@ASEUS.COM
Jr. Past Pres.:	Rolf Aschenbrenner	Rolf.Aschenbrenner@izm.fraunhofer.de
Executive Director:	Marsha Tickman	m.tickman@ieee.org

Elected Board Members

2012:	Chris Bailey, Daniel Donahoe, Paul D. Franzon, Daniel Lu, Kwang-Lung Lin, and Leonard W. Schaper
2013:	Debendra Mallik, Toni Mattila, James E. Morris, Eric Perfecto, Gilles Poupon, Dongkai Shangguan
2014:	Masahiro Aoyagi, Avram Bar-Cohen, Darvin R. Edwards, Beth Keser, Mervi Paulasto-Kröckel, CP Wong

CPMT Society Newsletter

Editor-in-Chief: Kitty Pearsall kittyp@us.ibm.com

CPMT Archival Publications

Transactions on Components, Packaging and Manufacturing Technology

Managing Editor:

R. Wayne Johnson

Co-Editor, Advanced Packaging:

Ravi Mahajan

Co-Editor, Electrical Performance:

José E. Schutt-Ainé

Co-Editor, Components: Characterization and Modeling:

Koneru Ramakrishna

Co-Editor, Packaging Technologies:

Kuo-Ning Chiang

Co-Editor, Electronics Manufacturing:

R. Wayne Johnson

Technical Committee Chairs

Interconnect & Substrate:

Kishio Yokouchi

Materials & Processes:

Rajen Chanchani

Nanotechnology:

James Morris

RF & THz Devices:

Craig Gaw

Energy Electronics:

Douglas Hopkins

Electrical Design, Modeling & Simulation:

Madhavan Swaminathan

Green Electronics:

Nils Nissen

Thermal & Mechanical:

Tony Mak

3D/TSV:

Paul Franzon

Emerging Technologies:

Erik Jung

Photonics – Communication, Sensing, Lighting:

Tolga Tekin

Strategic Program Directors

Global Chapters and Membership: Eric Perfecto, perfecto@us.ibm.com

Student Programs: Chris Bailey, C.Bailey@gre.ac.uk

Industry Programs: Phil Garrou, pgarrou/Contractor@rti.org

Region 8 Programs: Toni Mattila, toni.mattila@aalto.fi

Region 10 Programs: Kwang-Lung Lin, matkllin@MAIL.NCKU.EDU.TW

Standing Committee Chairs

Awards: Patrick Thompson, patrick.thompson@ti.com

Fellows Evaluation: CP Wong, cp.wong@ieee.org

Long Range / Strategic Planning: William Chen, william.chen@aseus.com

Nominations: Rolf Aschenbrenner, Rolf.Aschenbrenner@izm.fraunhofer.de

Distinguished Lecturers

Program Director: Kitty Pearsall, kittyp@us.ibm.com

Lecturers: Avram Bar-Cohen, Ph.D., H. Anthony Chan, Ph.D., Rajen Chanchani, Ph.D., William T. Chen, Ph.D., Badih El-Kareh, Ph.D., Xuejun Fan, Ph.D., Paul D. Franzon, Ph.D., Philip Garrou, Ph.D., George G. Harman, Ph.D., R. Wayne Johnson, Ph.D., George A. Katopis, Ph.D., John H. Lau, Ph.D., Michael Lebby, Ph.D., Ning-Cheng Lee, Ph.D., S. W. Ricky Lee, Ph.D., Johan Liu, Ph.D., James E. Morris, Ph.D., Kyung W. Paik, Ph.D., T. Paul Parker, Michael Pecht, Ph.D., Karl J. Puttlitz, Ph.D., Bahgat Sammakia, Ph.D., Dongkai Shangguan, Ph.D., Nihal Sinnadurai, Ph.D., Ephraim Suhir, Ph.D., Yong-Khim Swee, Yutaka Tsukada, Ph.D., Rao Tummala, Ph.D., Walter Trybula, Ph.D., E. Jan Vardaman, Paul Wesling, CP Wong, Ph.D., Ralph W. Wyndrum Jr., Ph.D., Kishio Yokouchi, Ph.D.

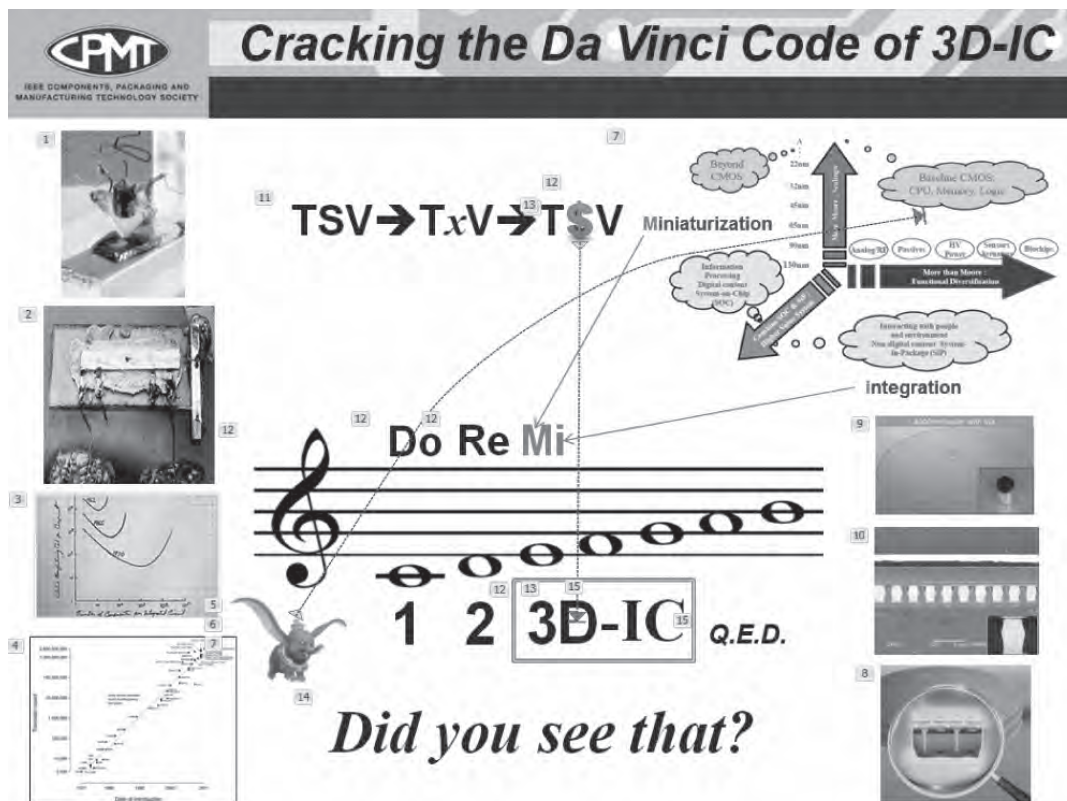
Chapters and Student Branches

Refer to cpmt.ieee.org for CPMT Society Chapters and Student Branches list

IEEE Components, Packaging, and Manufacturing Technology Society Newsletter is published quarterly by the Components, Packaging, and Manufacturing Technology Society of the Institute of Electrical and Electronics Engineers, Inc. Headquarters: 3 Park Avenue, 17th Floor, New York, NY 10016-5997. US \$1.00 per member per year is included in Society fee for each member of the Components, Packaging, and Manufacturing Technology Society. Printed in U.S.A. Periodicals postage paid at New York, NY, and at additional mailing offices. Postmaster: Send address changes to IEEE CPMT Newsletter, IEEE 445 Hoes Lane, Piscataway, NJ 08854. All rights reserved, copyright (c) 2012 by the CPMT Society of IEEE. Authors and Artists given full permission for further use of their contributions. For circulation information call IEEE Customer Service 800-701-4333, or FAX 908-981-9667.

**Circulate your printed or PDF copy of this
NEWSLETTER to co-workers.**

IEEE prohibits discrimination, harassment, and bullying. For more information, visit <http://www.ieee.org/web/aboutus/whatis/policies/p9-26.html>.



(Pictures extracted from various web sources)

“Cracking the Da Vinci Code of 3D-IC”? Sounds like the title of a mystery film or novel. But this is the title of my keynote presentation in a few recent CPMT-sponsored conferences and symposiums, which revealed my view on 3D-IC. With the aid of the PPT screen print above (instead of my regular dull portrait, again), I would try to render the presentation and idea to those who were not there.....

Starting from the infancy of electronics, I presented the pictures of two major milestones (at the upper-left corner), namely, the first point-contact semiconductor transistor (1947, William Shockley, Walter Brattain, John Bardeen) and the first integrated circuit (1958, Jack Kilby). The third picture on the left showed the original schematic drawing of Moore’s law (1965, Gordon Moore), followed by the fourth picture below which exhibited the modified Moore’s law for CPUs (1971–2011, Intel). In the ensuing four decades or so, the microelectronics era basically followed the Moore’s law steadily.

At the turn of the century, some new concepts started to evolve. The “Dumbo” flew from the lower-left corner across the slide to represent the emergence of disruptive technologies. The diagram at the upper-right corner is the famous ITRS figure for More Moore (MM) and More than Moore (MtM). The vertical red axis indicated the continuing trend of scaling, which actually implies “Miniaturization”. On the other hand, the horizontal blue axis exhibits the emerging trend of “integration”. I intentionally capitalized the former for a certain purpose later.

There exist several enabling technologies for MtM. Among them, the most well-known one is probably through-silicon vias

(TSV), which was illustrated by the picture at the lower-right corner in the above slide. In the past few years, the concept of TSV has been expanded to through-glass vias (TGV) and through-mold vias (TMV) as shown in the two photos above the TSV, respectively. Subsequently, some people suggested the term of “TSV” be generalized to “TxV”. In my humble opinion, no technologies could become successful if they are not cost effective. Therefore, I further recommended the terminology be modified to “T\$V”, as depicted at the top of the slide.

Now here comes the critical step. Let’s put the first letter of “Miniaturization” and that of “integration” together to form “Mi”. In the musical scale, “Mi” is the third note, after “Do” and “Re”. In other words, “Mi” represents “3”. Then the Dollar sign in “T\$V” at the top may drop down and stay next to “3”. This is how I deduced “3D” from “MM”, “MtM”, and “TSV”. In order to make sure the audience got the idea, I then posed the question: “Did you see that?” The answer must be “I see”. Otherwise, I would re-run the slide over and over again..... In case you still don’t get it, you may consider “IC” as the acronym for IEEE CPMT.

This is how I cracked the *Da Vinci code* of 3D-IC from the perspective of packaging trends. Q.E.D. (*quod erat demonstrandum*) I hope you enjoyed it!

Prof. S. W. Ricky Lee, IEEE Fellow, President IEEE CPMT Society, Hong Kong University of Science and Technology, Kowloon, Hong Kong, rickylee@ieee.org

New IEEE CPMT Senior Members

Congratulations to the members listed below who were recently elevated to the grade of Senior Member.

The grade of Senior Member is the highest for which application may be made and shall require experience reflecting professional maturity. For admission or transfer to the grade of Senior Member, a candidate shall be an engineer, scientist, educator, technical executive, or originator in IEEE designated fields for a total of 10 years and have demonstrated 5 years of significant performance.

Individuals may apply for Senior Member grade online at: www.ieee.org/web/membership/senior-members/index.html

Dries Vande Ginste
Parthiban Arunasalam
Marie Cote

Vicente Gonzalez Millan
Kirk Gray
Mike Hamilton

HingWah Lee
Yuriy Shlepnev
Michael Töpper

CPMT Society Welcomes New and Returning Members

The Members listed below either joined or rejoined the CPMT Society between 1 August and 17 October 2012. Join us in welcoming them to the CPMT Community.

Harold Arbelaez Duque	Colombia Section
Jung Hyung Bae	Seoul Section
Jeanette Brooks	Boise Section
Alan Brownell	Charlotte Section
Kihun Chang	San Diego Section
Daniel Deisz	Northern Virginia Section
Robin Dykstra	New Zealand Central Section
Weileun Fang	Taipei Section
Michel Fleury	Ottawa Section
Bih Wen Fon	Malaysia Section
Robert Gardyne	Oakland-East Bay Section
Gary Grimm	Seattle Section
Paul Jacob	Santa Clara Valley Section
Dennis Kehl	West Michigan Section
Ling Eng Khoong	Singapore Section
Kati Kokko	Benelux Section
Christopher Laplante	Denver Section

Jun Li
Bruce Lowther
Christopher Mazique
James Nadolny
Zainal Abidin Nordin
Stefano Oggioni
Kenny Otiaba
Michael Rattner
Cindi Rose
Max Schneiderman
Ramya Shankar
Robert Sokolovskij
Venkatasubramanian Srinivasan
Ken-Ichi Takeda
Rui Victal
David Williams
Min-Feng Yu

Santa Clara Valley Section
Northern Virginia Section
Atlanta Section
Susquehanna Section
Malaysia Section
Italy Section
U.K. & Rep Of Ireland Section
San Francisco Section
Twin Cities Section
Miami Section
Santa Clara Valley Section
Benelux Section
Madras Section
Tokyo Section
Toronto Section
West Michigan Section
Atlanta Section

Call for Nominations for the 2013 CPMT Society Awards

Nominations Due by January 31, 2012

The CPMT Society is full of highly talented professionals, and we have five awards to recognize those who have performed at an exceptional level. Do you have a friend or colleague who has made outstanding contributions to the technical fields within CPMT? Would you like him or her to receive recognition for these contributions? We would, too; you can make it happen by submitting a nomination today.

The Awards Committee is currently accepting nominations for the 2013 CPMT Awards. All nomination packages are due by January 31, 2013. Winners will be notified by April 15, 2013, and the awards will be presented at the 63rd Electronic Components and Technology Conference, May 28–31, 2013, in Las Vegas, Nevada, USA. A current nomination form can be found on the CPMT web site under the Awards link at: <http://cpmt.ieee.org/awards.html>. We look forward to receiving your nominations for any of the awards described below.

CPMT Society offers the following awards for the purpose of recognizing outstanding service and contributions to the professional purposes of the CPMT Society.

David Feldman Outstanding Contribution Award: To recognize outstanding contributions to the fields encompassed by the CPMT Society through executive or managerial directions.

Prize: \$2,500 and Certificate

Basis for Judging: Contributions to the organization or enterprises connected with the field, to CPMT Chapter, Section or Board of Governors activities, and to the fields encompassed by the CPMT Society.

Eligibility: Recipient must have been a member of IEEE and CPMT for the past five (5) years, including 2012.

Outstanding Sustained Technical Contributions Award: To recognize outstanding sustained and continuing contributions to the technology in fields encompassed by the CPMT Society.

Prize: \$2,500 and Certificate

Basis for Judging: Technical contributions must be sustained and continuing over a period of at least five (5) and preferably 10 years. One major contribution will not qualify. Contributions must be documented by open literature publications such as papers, patents, books and reports (available to the public).

Eligibility: Must have been a member of the IEEE and CPMT Society for the past three (3) years, including 2012.

Electronics Manufacturing Technology Award: To recognize major contributions to Electronic Manufacturing Technology in fields encompassed by the CPMT Society.

Prize: \$2,500 and Certificate

Basis for Judging: Contributions may include technical development of, or management (directing) of major new electronic manufacturing processes; significantly increasing yield and/or reliability of established manufacturing processes, etc. Work in the management of CPMT conferences or its BoG may be contributory but not sufficient to receive the award.

Eligibility: No need to be a member of IEEE and CPMT Society.

Exceptional Technical Achievement Award: To recognize an individual, or group of individuals (no more than three), for exceptional technical achievement in the fields encompassed by the CPMT Society.

Prize: \$2,500 and a Certificate.

Basis for Judging: Technical contributions of the nominee(s) must be such that they are considered to be exceptional, not achieved by most members. A single major contribution will qualify for this award. The contribution could be a significant invention, introduction of a significantly new and important technology or product (in which case, the nominee may be a team leader), or significant work that advances the state-of-the-art in CPMT's field of interest. The technical contributions must be documented by open literature publications such as papers, patents, books, and reports (available to the public). Technical recognition and awards from the organization employing the individual as well as awards from other IEEE and non-IEEE technical societies may also be contributory.

Eligibility: Recipient(s) must have been a member of IEEE and CPMT for the past three (3) years, including 2012. There are no requirements for service to the IEEE or CPMT Society.

Outstanding Young Engineer Award: To recognize outstanding contributions to the fields encompassed by the CPMT Society through invention, technical development, publications, or new product implementation.

Prize: \$1,500 and Certificate

Basis for Judging: Technical contributions through patent invention, contributions to technology or product development within the CPMT Field of Interest. May encompass management (directing) of significant new product introduction or implementation of major new electronic manufacturing processes; significantly increasing yield and/or reliability of established manufacturing processes. Contributions to the Society, through the BoG, Conferences, Chapters, etc., will also be considered. Proof of contributions may consist of open literature publications (preferred) such as papers, patents, books, and reports (available to the public). At least three (3) letters from peers and management at the nominee's place of employment attesting to the accomplishment(s) can be accepted in lieu of publications.

Eligibility: Must have been a member of the IEEE and CPMT (member grade or above) for the past three (3) years, including 2012, and must be 35 years of age, or younger, on December 31, 2012.

Guidelines for Nominators:

- Past recipients of an award are not eligible to receive that same award. For lists of past awardees, see <http://cpmt.ieee.org/awards.html>
- An individual may submit only one nomination per award but may submit nominations for more than one award.
- It is the responsibility of the nominator to provide quality documentation to assist the Awards Committee in evaluating the candidate.
- Please send nominations to CPMT Society Awards Committee Chair by e-mail (preferred) or mail:

Patrick Thompson
Texas Instruments
13020 TI Blvd, MS3521, Dallas, TX 75243,
patrick.thompson@ti.com

Chapter News....

IEEE CPMT UK&RI Chapter

*Research to Industry (R2i) Workshop, 19th June 2012 at
Henry Ford Centre, Loughborough, UK*

Submitted by Nihal Sinnadurai, Chair IEEE CPMT UK&RI

The objective of R2i was to provide an opportunity for industry take-up of good developmental research. The initiative was sponsored jointly by IEEE, IMAPS-UK and the UK's IeMRC (electronics manufacturing research centre). A very disciplined programme was arranged. A template was created for the sessions and presentations. The programme comprised 4 sessions, each led by a relevant Keynote practitioner or government funding representative, such as those listed below.

The National Microelectronics Institute (NMI) gave an overview of the mechanisms that were available for the funding of research projects, the pathways and requirements. The huge range of potential funding routes was also outlined.

The Knowledge Transfer Partnerships (KTP), managed by the Technology Strategy Board. KTPs were described as a mechanism for providing a commercial pull to research carried out at Universities. KTP projects typically lasted from 6 months to 3 years, with 2 years being the preferred duration. The associate worker on a KTP project would be jointly recruited but employed by the knowledge base partner and typically located at the business prem-

ises. KTPs required innovative projects with a strategic relevance to the business and that had a clear knowledge transfer element creating a step change in capability.

The IeMRC director spoke on "The journey of a successful project"—outlining some of the key challenges of taking research up the technology readiness levels towards commercial implementation. The UK government has acknowledged the need to get more of the UK's successful research into industry, where its benefits could be utilised and he cited, by way of example, the recent announcement of substantial funding to support the development of graphene in the UK.

The presenter from the Centre for Process Innovation (CPI) addressed electronics capability in the High Value Manufacturing Catapult Centre. Two influential reports by James Dyson and Herman Hauser had highlighted the problems of getting new technology to market. The Catapult Centres were aimed at bridging the gap (the valley of death) between academia and industry take-up.

At each session, the Researchers presented their results in tight 5-minute slots before an audience which included industry players. The aim was to stimulate take-up of the research by industrialists and venture funders to lead to development, manufacture and the market.

IEEE UK&RI takes a strong interest in good research. At the R2i event we praised the good research and recognised outcomes that were worthy of take-up from industry.

As an example of research en-route to industry take-up, Liudi's research on MEMS application of carbon nanotubes to fabricate advanced electrical contacts for MEMS switches capable of switching >10 mA at up to 4 V over >108 cycles. MEMS switch/relays had been forecast to be a multibillion dollar technology area but technical barriers were the lack of switches and the need for high conductivity, reliability and long lifetimes. The reliability work indicated that CNT based devices could provide extended switching cycles compared with more conventional switching, that it was possible to switch 20 mA at 4 V for more than > 80 million cycles.

The R2i event was well attended by researchers but more venture participation was needed. We will try the event again in 2013.



Nihal Sinnadurai (left), Chair IEEE UK&RI, congratulates Liudi Jiang from Southampton University.

Publication News....

CPMT Transactions Offers Open Access Publishing Option

The *IEEE Transactions on Components, Packaging and Manufacturing Technology* offers its authors the option to publish articles either for Traditional publication or for Open Access (OA) publication.

The majority of IEEE Transactions operate according to this model and are known as hybrid journals.

The Traditional manuscript option is a continuation of the long-standing approach in which published articles are available to all

qualified subscribers and purchasers via IEEE Xplore. Authors only pay fees for overlength pages, if applicable or for color images in print, if they choose this option.

The OA option enables unrestricted public access to the article via IEEE Xplore. The OA option will be offered to the author at the time the article is submitted for review. If selected, the author must pay the OA fee (discounted rate of US\$1750 per article) before the article is published in the *Transactions*.

The IEEE peer review standard of excellence is applied consistently to all submissions. All accepted articles will be included in the print issue mailed to those who subscribe to print.

A banner graphic for IEEE Open Access. It features a dark background with a stylized globe in the center, overlaid with a grid of white lines. Surrounding the globe are several white circular nodes connected by lines, resembling a network or molecular structure. The text "IEEE Open Access" is prominently displayed in white, with the tagline "Unrestricted access to today's groundbreaking research via the IEEE Xplore® digital library" below it.

IEEE Open Access

Unrestricted access to today's groundbreaking research via the IEEE Xplore® digital library

IEEE offers a variety of open access (OA) publications:

- Hybrid journals known for their established impact factors
- New fully open access journals in many technical areas
- A multidisciplinary open access mega journal spanning all IEEE fields of interest

Discover top-quality articles,
chosen by the IEEE peer-review
standard of excellence.

Learn more about IEEE Open Access
www.ieee.org/open-access



Have You Read Them? The Most Downloaded CPMT Transactions Papers

What might you be missing in the CPMT literature? Following is a list of most downloaded papers from the Transactions on Components, Packaging and Manufacturing Technology in Third Quarter 2012. Subscribers can access these and other papers in IEEE Xplore (<http://ieeexplore.ieee.org/xpl/RecentIssue.jsp?punumber=5503870#>).

A Compact and Embedded Balanced Bandpass Filter With Wideband Common-Mode Suppression on Wireless SiP

Hung-Chuan Chen; Chung-Hao Tsai; Tzong-Lin Wu; Volume: 2, Issue: 6, Publication Year: 2012, Page(s): 1030–1038

A compact balanced bandpass filter is proposed using a novel circuit topology, which includes a differential resonator and a common resonator in the conventional quasi-lumped coupled-line circuit, instead of adopting quarter-wavelength or half-wavelength transmission lines in the filter design. Based on this circuit topology, the balanced bandpass filter can support bandpass filtering function under differential-mode operation and exhibit bandstop filtering function under common-mode noise. By employing the advantage of the low-temperature co-fired ceramic fabrication technology, a compact balanced bandpass filter is centered at 3.42 GHz with fractional bandwidth 10.4% for differential signals and rejection band is from 1.48 to 7.4 GHz for the common-mode noise. Moreover, the proposed filter is able to introduce a transmission zero with excellent common-mode suppression (>40 dB) within the differential-mode passband. The electrical size of this filter is 5.6×5.4 mm with the corresponding electrical size $0.113 \times 0.109 \lambda_g$, where λ_g is the guided wavelength at the center frequency 3.42 GHz. This compact balanced bandpass filter is suitable to be applied to the system-in-package technology for wireless application.

Embedded Module for 3-D Mechanical Strain Measurement

Moore, L.; Barrett, J.; Volume: 2, Issue: 6, Publication Year: 2012, Page(s): 1002–1011

This paper presents the development and evaluation of a miniature (1 cm^3) embedded electronic module that can resolve temperature-compensated mechanical strain in three dimensions. The module is designed to be embedded into materials and to measure, in-situ, all nine components of strain and to relay the information back to a PC via wired communications. The module can also be assembled as a component in a “parent” encapsulated electronic system and interface with the system’s digital bus. The module comprises three miniature, off-the-shelf, three-gauge, rectangular rosettes that are assembled in a 3-D array so that all components of strain can be resolved. The module format is a cube, with the gauges on the outer faces of the cube, and the electronics on the inside. The electronics consists of signal conditioning circuitry, a 24-bit sigma-delta ADC, a microcontroller which sends the digital data directly to a master device such as PC, and an onboard temperature sensor for thermal compensation of the gauges. The module was evaluated by encapsulating it in epoxy and subjecting it to compressive and tensile testing in a mechanical tester. The results were compared to

finite element simulations with an average of 7% difference between magnitudes and a standard deviation of 4%. Thermal evaluation of the module was also carried out by subjecting the test pieces to thermal loads and monitoring the response of the system. The module is believed to be the smallest yet reported self-contained, embedded system capable of resolving all components of 3-D strain, it is small enough to be embedded in a wide range of materials and structures without significant impact on the mechanical properties of its host. It can, therefore, be used in applications such as structural health monitoring and reliability prognostics and for calibration of mechanical/thermo-mechanical simulations.

High-Frequency Scalable Electrical Model and Analysis of a Through Silicon Via (TSV)

Joohee Kim; Jun So Pak; Jonghyun Cho; Eakhwan Song; Jeon-gyeon Cho; Heegon Kim; Taigon Song; Junho Lee; Hyungdong Lee; Kunwoo Park; Seungtaek Yang; Min-Suk Suh; Kwang-Yoo Byun; Joung-ho Kim; Volume: 1, Issue: 2, Publication Year: 2011, Page(s): 181–195

We propose a high-frequency scalable electrical model of a through silicon via (TSV). The proposed model includes not only the TSV, but also the bump and the redistribution layer (RDL), which are additional components when using TSVs for 3-D integrated circuit (IC) design. The proposed model is developed with analytic *RLGC* equations derived from the physical configuration. Each analytic equation is proposed as a function of design parameters of the TSV, bump, and RDL, and is therefore, scalable. The scalability of the proposed model is verified by simulation from the 3-D field solver with parameter variations, such as TSV diameter, pitch between TSVs, and TSV height. The proposed model is experimentally validated through measurements up to 20 GHz with fabricated test vehicles of a TSV channel, which includes TSVs, bumps, and RDLs. Based on the proposed scalable model, we analyze the electrical behaviors of a TSV channel with design parameter variations in the frequency domain. According to the frequency-domain analysis, the capacitive effect of a TSV is dominant under 2 GHz. On the other hand, as frequency increases over 2 GHz, the inductive effect from the RDLs becomes significant. The frequency dependent loss of a TSV channel, which is capacitive and resistive, is also analyzed in the time domain by eye-diagram measurements. Due to the frequency dependent loss, the voltage and timing margins decrease as the data rate increases.

Characterization of Heat Dissipation From a Microprocessor Chip Using Digital Interferometry

Sajith, V.; Sobhan, C.B.P.; Volume: 2, Issue: 8, Publication Year: 2012, Page(s): 1298–1306

Electronic circuit boards of computers consist of components which generate substantial amounts of heat during their operation. Among these, the microprocessor chip is one of the major sources of heat generation. In high-performance processor chips, the rates of heat generation are also correspondingly high. The performance of the chips themselves, as well as that of the neighboring electronic components are affected by the temperature levels attained, which in turn depend on the heat dissipation capability. Effective thermal management of microprocessor chips, following precise thermal characterization, is essential to avoid their untimely

failure due to overheating. The selection of an appropriate cooling methodology and the design of an efficient cooling system for the microprocessor chip essentially require a clear knowledge of the heat dissipation rates during its operation. A comprehensive database of heat dissipation from microprocessor chips as a function of the activity level, based on actual measurements, is rare to find in the literature. A major reason for this is that conventional intrusive measurements on and around the chip are quite insufficient, as they will alter the performance, while the system is under operation. To overcome this, a nonintrusive digital interferometric measurement has been devised in this paper for obtaining the in situ temperature distributions and the heat dissipation patterns around the microprocessor chip, while it is under operation. The interferometric method utilizes interference of coherent laser beams to make measurements in the thermal field around the heat-dissipating component. An Intel Pentium 4 microprocessor with its integrated heat sink was used for experimentation. The computational load on the processor was varied utilizing a software package, thus varying the heat generation rates, and the base temperature of the fins in the heat sink attached to the microprocessor. Interferometric measurements were made to obtain the temperature distribution in the medium, and the patterns of heat dissipation from the fins' surfaces. Indicators of the heat transfer behavior, namely, the local heat flux values and the heat transfer coefficients were obtained from the experiments, using digital image processing techniques. Experiments were conducted at various fin-base temperatures, under free and forced convection conditions, to characterize the effect through a database of the heat dissipation level. In essence, a nonintrusive temperature measurement method coupled with digital image processing techniques has been successfully used for convective heat transfer studies on the microchip while the microchip is under operation.

Affordable Ink-Jet Printed Antennas for RFID Applications

Pranonsatit, S.; Worasawate, D.; Sritanavut, P.; Volume: 2, Issue: 5; Publication Year: 2012, Page(s): 878–883

With the increasing demands of radio-frequency identification (RFID) applications, an alternative ink-jet printing technique for RFID tag antenna is demonstrated. Commercially available ink-jet printers are adapted for conductive printing, in order to minimize manufacturing cost. Paper-based dipole antenna and dipole with a tuning stub antenna were designed. The antennas were ink-jet printed and assembled with RFID chips. The performances of the fabricated tags were measured through the reading range. With reference to equivalent isotropically radiated power of 4 W at 923 MHz, the reading range of tag with dipole antenna is around 9 m and of tag with dipole with a tuning stub is nearly 13 m. These performances are comparable to those of commercial tags. The advantages of the proposed printing technique are simplicity, flexibility and, more importantly, affordability. The technique can, in addition, contribute to further development and enhance extension of RFID applications.

PDN Impedance Modeling and Analysis of 3D TSV IC by Using Proposed P/G TSV Array Model Based on Separated P/G TSV and Chip-PDN Models

Jun So Pak; Joohee Kim; Jonghyun Cho; Kiyeong Kim; Taigon Song; Seungyoung Ahn; Junho Lee; Hyungdong Lee; Kunwoo

Park; Joungho Kim; Volume: 1, Issue: 2; Publication Year: 2011, Page(s): 208–219

The impedance of a power-distribution network (PDN) in three-dimensionally stacked chips with multiple through-silicon-via (TSV) connections (a 3D TSV IC) was modeled and analyzed using a power/ground (P/G) TSV array model based on separated P/G TSV and chip-PDN models at frequencies up to 20 GHz. The proposed modeling and analysis methods for the P/G TSV and chip-PDN are fundamental for estimating the PDN impedances of 3D TSV ICs because they are composed of several chip-PDNs and several thousands of P/G TSV connections. Using the proposed P/G TSV array model, we obtained very efficient analyses and estimations of 3D TSV IC PDNs, including the effects of TSV inductance and multiple-TSV inductance, depending on P/G TSV arrangement and the number of stacked chip-PDNs of a 3D TSV IC PDN. Inductances related to TSVs, combined with chip-PDN inductance and capacitance, created high upper peaks of PDN impedance, near 1 GHz. Additionally, the P/G TSV array produced various TSV array inductance effects on stacked chip-PDN impedance, according to their arrangement, and induced high PDN impedance, over 10 GHz.

Modeling and Analysis of Through-Silicon Via (TSV) Noise Coupling and Suppression Using a Guard Ring

Jonghyun Cho; Eakhwan Song; Kihyun Yoon; Jun So Pak; Joohee Kim; Woojin Lee; Taigon Song; Kiyeong Kim; Junho Lee; Hyungdong Lee; Kunwoo Park; Seungtaek Yang; Minsuk Suh; Kwangyoo Byun; Joungho Kim; Volume: 1, Issue: 2; Publication Year: 2011, Page(s): 220–233

In three-dimensional integrated circuit (3D-IC) systems that use through-silicon via (TSV) technology, a significant design consideration is the coupling noise to or from a TSV. It is important to estimate the TSV noise transfer function and manage the noise-tolerance budget in the design of a reliable 3D-IC system. In this paper, a TSV noise coupling model is proposed based on a three-dimensional transmission line matrix method (3D-TLM). Using the proposed TSV noise coupling model, the noise transfer functions from TSV to TSV and TSV to the active circuit can be precisely estimated in complicated 3D structures, including TSVs, active circuits, and shielding structures such as guard rings. To validate the proposed model, a test vehicle was fabricated using the Hynix via-last TSV process. The proposed model was successfully verified by frequency- and time-domain measurements. Additionally, a noise isolation technique in 3D-IC using a guard ring structure is proposed. The proposed noise isolation technique was also experimentally demonstrated; it provided –17 dB and –10 dB of noise isolation between the TSV and an active circuit at 100 MHz and 1 GHz, respectively.

Wafer Bumping, Assembly, and Reliability of Fine-Pitch Lead-Free Micro Solder Joints for 3-D IC Integration

Ching-Kuan Lee; Tao-Chih Chang; Lau, J.H.; Yu-Jiau Huang; Huan-Chun Fu; Jui-Hsiung Huang; Zhi-Cheng Hsiao; Cheng-Ta Ko; Ren-Shin Cheng; Pei-Chen Chang; Kuo-Shu Kao; Yu-Lan Lu; Lo, R.; Ming-Jer Kao; Volume: 2, Issue: 8, Publication Year: 2012, Page(s): 1229–1238

In this investigation, Cu-Sn lead-free solder microbumps on 10- μ m pads with a 20- μ m pitch are designed and fabricated. The

chip size is 5×5 mm with thousands of microbumps. A daisy-chain feature is adopted for the characterization and reliability assessment. After pattern trace formation, the microbump is fabricated on the trace by an electroplating technique. A suitable barrier/seed layer thickness is designed and applied to minimize the undercut due to wet etching but to still achieve good plating uniformity. With the current process, the undercut is less than $1\text{ }\mu\text{m}$ and the bump height variation is less than 10%. In addition, the shear test is adopted to characterize the bump strength, which exceeds the specification. Also, the Cu-Sn lead-free solder microbumped chip is bonded on an Si wafer using chip-to-wafer bonding technique. Furthermore, the microgap between the bonded chips is filled with a special underfill. The shear strength of the bonded chips without the underfill is measured and it exceeds the specification. The bonding and filling integrity is further evaluated by open/short measurement, scanning acoustic tomography analysis, and cross-section with scanning electron microscopy analysis. The stacked ICs are evaluated by reliability (thermal cycling) test (-55 to 125°C). Finally, ultra-fine-pitch ($5\text{-}\mu\text{m}$ pads on a $10\text{-}\mu\text{m}$ pitch) lead-free solder micro-bumping is explored.

Compact High-Gain mmWave Antenna for TSV-Based System-in-Package Application

Sanming Hu; Yong-Zhong Xiong; Lei Wang; Rui Li; Jinglin Shi; Teck-Guan Lim; Volume: 2, Issue: 5; Page(s): 841–846

This paper presents a cavity-backed slot (CBS) antenna for millimeter-wave applications. The cavity of the antenna is fully filled by polymer material. This filling makes the fabrication of a silicon CBS antenna feasible, reduces the cavity size by 76.8%, and also maintains the inherent high-gain and wide bandwidth. In addition,

a through-silicon via-based architecture is proposed to integrate the 135-GHz CBS antenna with active circuits for a complete system-in-package. Results show that the proposed structure not only reduces the footprint size but also suppresses the electromagnetic interference.

Development of Wafer-Level Warpage and Stress Modeling Methodology and Its Application in Process Optimization for TSV Wafers

Faxing Che; Li, H.Y.; Xiaowu Zhang; Shan Gao; Teo, K.H.; Volume: 2, Issue: 6, Publication Year: 2012, Page(s): 944–955

Through-silicon via (TSV) technology has been widely investigated recently for 3-D electronic packaging integration. Reducing TSV wafer warpage is one of the most challenging concerns for successfully subsequent processes. In this paper, a wafer-level warpage modeling methodology has been developed by the finite element analysis method using an equivalent material model. The developed modeling methodology has been verified by numerical results and experimental data. Using the developed model, wafer warpage has been simulated and analyzed by considering different factors, such as annealing temperature, copper (Cu) overburden thickness, TSV depth, and diameter. Simulation results show that wafer warpage increases with increasing annealing temperature and Cu overburden thickness. Such findings have been successfully used in TSV process optimization to reduce wafer warpage after annealing process. A global-local modeling methodology has also been implemented to determine wafer stress accurately. Wafer bending stress is high at wafer surface and close to TSV edge. Wafer bending stress increases with increasing TSV diameter and it is higher at the edge of TSVs with finer pitch.

IEEE Xplore

Table of Contents Alert

Any technologist – **member or non-member** – is welcome to receive alerts when upcoming issues of our CPMT *Transactions* are posted to the IEEE's Xplore database and all the papers are available for downloading. This is a handy way to scan the issue's Table of Contents and quickly learn about novel approaches to packaging, modeling, reliability, materials, assembly and other topics.

The website link is: ieeexplore.ieee.org/xpl/tocalerts_signup.jsp

If you already have an IEEE web account, you may sign in and select those journals you wish to track. If you don't have an account, all it takes is your name and email address! Then simply click the Alert Status box next to the journals you wish to monitor. You will receive an email each quarter when that journal is posted to Xplore.

Similarly, if you prefer to receive information by RSS feed, you may add our journals' feeds to your Reader. You'll get a listing of the papers in that issue, along with full abstracts and a link for downloading the paper. The RSS links are shown on this same web page.

Here are the journals we suggest you select for monitoring:

Transactions on Components, Packaging and Manufacturing Technology
Transactions on Semiconductor Manufacturing

Now... 2 Ways to Access the IEEE Member Digital Library

With two great options designed to meet the needs—and budget—of every member, the IEEE Member Digital Library provides full-text access to any IEEE journal article or conference paper in the IEEE *Xplore*® digital library.

Simply choose the subscription that's right for you:

IEEE Member Digital Library

Designed for the power researcher who needs a more robust plan. Access all the IEEE content you need to explore ideas and develop better technology.

- 25 article downloads every month

IEEE Member Digital Library Basic

Created for members who want to stay up-to-date with current research. Access IEEE content and rollover unused downloads for 12 months.

- 3 new article downloads every month

Get the latest technology research.

**Try the IEEE Member Digital Library
—and get your FIRST MONTH FREE!**

www.ieee.org/go/freemonth



IEEE Member Digital Library is an exclusive subscription available only to active IEEE members.

Conference News....

2012 IEEE Semiconductor Wafer Test Workshop

*Submitted by Jerry Broz, Ph.D., General Chair of
IEEE SW Test and IEEE Senior Member*

*Ira Feldman, IEEE Member and Executive Committee
of IEEE SFBA Nanotechnology Council*

Wafer level test and probe technologists met in San Diego, CA, from June 10 to 13, 2012 for the 22nd Annual IEEE Semiconductor Wafer Test Workshop (SW Test) at the Rancho Bernardo Inn. This annual IEEE/CPMT sponsored workshop brings together technologists, engineers, and managers as well as sales and marketing professionals involved with all aspects of probe technology and wafer level testing. This year, SW Test had a total of 357 attendees from 15 countries with 28% of the attendees from outside the US for a global gathering of leading technologists and related suppliers. The 2012 Workshop drew a great mix of end-users (~31%) and suppliers/vendors (~69%) for the technical program and exhibition during the three day event. This unique workshop promotes a friendly networking environment between colleagues, new attendees, salesman/marketers, and students. The grassroots agenda provides for plenty of time to have informal interaction and discussions.

The SW Test Program began with a Sunday tutorial from Doug Sottaway of Intel Corporation on the basics of Process Control Systems with applicability to wafer level sort. Mr. Sottaway discussed the strength of decision making based on process feedback for wafer sort improvements. This tutorial was a valuable follow-on to the Statistics Tutorial that was made by Lance Milner, also of Intel, at SW Test 2011.

On Sunday night, Matt Nowak, Senior Director, Advanced Technology, Qualcomm CDMA Technologies, provided an informative keynote presentation entitled “*Emerging High Density 3D Through Silicon Stacking (TSS) – What’s Next?*” Mr. Nowak began with examples of Thru Silicon Vias (TSVs) technology that have been in high volume production for image sensors for several years now; but at a significantly lower density than for 3D packaging. The great interest in 3D packaging is driven by the “mega-economic” trend for the electronics industry, that predicts ~29% per year cost reductions and pushes new lower cost solutions, especially when wafer fabrication processes become more expensive. As demands for mobile devices continue to dominate the market, critical issues of improved performance, greater power efficiency, continued miniaturization, and cost reduction must be addressed.

Mr. Nowak expanded on the three key reasons behind 3D TSV packaging – power, form factor, and economics. Power management is not just the concern over battery life of a mobile device. As mobile devices continue to gain more functionality, there is an upper limit on how fast they can operate and how many processor cores can be active at a time. As an example, mobile phones can dissipate about 3 Watts of power before the device becomes “too hot handle”, i.e., handheld case temperature exceed 40 C. In many applications, especially mobile devices which everyone wants to be smaller or which require a larger battery to operate longer, there

is a concern over the 3D volume of semiconductor package not just the planar 2D size. From the economics side, the consumer wants lower cost devices with better performance; regardless of the manufacturing costs. 3D packaging helps to address all of these challenges and, as such, Qualcomm has been building 3D parts with up to five stacked die.

Today the limit to stacking is economics based upon yield, cost of test, and ability to repair defects once stacked. To control costs, Qualcomm has examined using two die from older process nodes in a 3D package versus building a single die in the latest process node. This approach can accelerate time to market (when a newer process node is not yet ready) or where the die is extremely large (resulting in very low initial yields at the newer process node).

The industry has developed a long list of concerns in regards to implementing 3D packaging using TSVs which include reliability testing, processing, design for memory die on logic die, product concerns, and TSV technical challenges. Mr. Nowak highlighted a few areas that still remain the most problematic: (1) Testability – test methods and needed infrastructure are still being developed and no solutions exist for repair after assembly, e.g., how to correct for an assembly process defect or a defect in each die discovered after the stack is assembled; (2) Yield & High Volume – many yield issues, including process sensitivities, only become apparent once products are ramped to high volume; and (3) Design Challenges – device and chip set interactions that may impact product reliability must be considered for 3D package design. For example, it is undesirable to have the hot spots (areas that tend to heat up faster) on each die aligned in the stack; or, there may be similar localized mechanical stresses on each die that interact once stacked resulting in device failure or reliability problems.

Mr. Nowak concluded by saying that the semiconductor “game” is changing; it is no longer about architecture and differentiation in the future will come from packaging. It is really the system software and chipset architecture that will drive the product. In fact, over two-thirds of the engineers at Qualcomm are software engineers and the 3D packaging of stacked chips provides a “new bag of tricks” for chipset architects. Momentum is building in the development of TSV technology and associated infrastructure to make 3D packaging; however, the biggest challenge currently is the high prices from suppliers.

In terms of product development, Mr. Nowak expects to see memory stacking (especially for higher value data center applications and to replace the package-on-package stacks of memory on microprocessors) followed by 2.5D interposer applications, then logic-on-logic applications and finally 3D stacks side-by-side on interposers. These developments will present plenty of challenges in stacking silicon and opportunities to keep the industry quite busy. Matt Nowak’s keynote entire presentation is available for download on the SW Test website (<http://www.swtest.org>).

On Monday morning, Dr. Jerry Broz, SW Test General Chair, welcomed the attendees to the 22st Annual SW Test Workshop. Dr. Broz reviewed a number of SIA and WSTS statistics; however, since Intel and AMD withdrew from WSTS and SICAS was

discontinued after Nanya Technology, Taiwan Semiconductor Manufacturing Company Ltd. (TSMC) and United Microelectronics Corporation (UMC) withdrew, the semiconductor industry lost definitive sources of capacity and utilization data, a key component in determining current and near term industry conditions.

The VLSI Research probe card market overview (released in May, 2012) showed that the total probe card revenue was up slightly in 2011, a gain of ~17% (from ~\$999M in 2010 to ~\$1170M in 2011). The top three revenue generating probe card suppliers saw a change for the first time in almost 10 years – (1) Micronics Japan (MJC); (2), FormFactor, Inc. (FFI); and (3) Japan Electronic Materials (JEM). Of the top five probe card suppliers, MicroProbe reported the greatest percentage growth while FormFactor experienced the largest decrease in revenue from 2010.

Dr. Broz announced that the IEEE William R. Mann Student Travel Grant was awarded to Mr. Soheil Khavandi from the University of Nevada, Reno. This grant supports undergraduate or graduate student participation at IEEE ITC or IEEE SW Test (one grant per conference per year). After the Chairman's Welcome to Attendees, the technical program kicked-off and the excellent podium presentations covered various facets of the wafer test process from *Process Improvements for HVM to New Probe and Contactor Technologies to Fine Pitch Probing Challenges*. The next three days were filled with a broad technical program; with 5-hours of supplier exhibits (which did not compete with the technical sessions), and a Hawaiian Luau Social Event to promote friendly networking amongst the international attendees.

Individual highlights from the technical program included a discussion by Doron Avidar (Micron – Israel) for process improvements using “ghosting” for touchdown reduction for alternate site sharing. Understanding key issues of overtravel control with advanced probe cards was discussed by Tommie Berry (FFI) in a collaborative effort with Freescale Semiconductor. Bernd Bischoff (Texas Instruments – Germany) discussed pad aluminum thickness effects for process control, cleaning optimization, and probe card lifetime extension. Stevan Hunter (ON Semiconductor) presented continuing investigations into bond pad cracking under harsh probing with three different probe card technologies. Kong Meng Hui (ISS-NUS – Singapore) discussed using of artificial intelligence concepts for interpreting wafer maps. Ira Feldman (Feldman Engineering Corp.) discussed the test challenges and possible solutions for the transition to 450 mm. Dr. Raffaele Vallauri (TechnoProbe – Italy) introduced a new vertical MEMS solution for high current, low pitch applications. Gert Hohenwarter, Ph.D., (Gatewave Northern) outlined fine pitch high performance needle probe concept using novel micro-plating technique. Jose Horas (Intel Mobile Communications - Germany) presented a study focused on 28nm mobile SoC copper pillar probing study. Test and measurement challenges for 3D IC development were presented by Raphael Robertazzi, Ph.D. (IBM Research). Senthil Theppakuttai, Ph.D. (SV Probe) and Todd Tsao (ASE Global – Taiwan) covered the challenges of advanced Cu-pillar applications at 50µm for enabling fine pitch probing. John Strom (Rudolph Technologies) proposed innovative approaches and concepts for reducing the cost of probe card test. Developments with a novel



IEEE SW Test Committee 2012: Front (L): Tatsuo Inoue, John Caldwell, Jerry Broz, Ph.D. (General Chair), Patrick Mui, Mark Ojeda, Amy Leong, Fred Taber, Darren James. Back (L): Matt Zeman, Ph.D., Jan Martens, Rey Rincon (Program Chair), Michael Huebner, Ph.D., Gunther Boehm. Not pictured: Boyd Daniels

carbonaceous film with high electrical conductivity and ultra high hardness for test probes were presented by Dr. Teruyuki Kitagawa (Nomura Plating, Co., Ltd. - Japan). Detailed summaries from all of the technical sessions (including the questions & answers) from all of the technical sessions can be found at Ira Feldman's Blog at <http://hightechbizdev.com/>.

Overall, the technical program had 29 podium presentations with 59% from suppliers, 15% from semiconductor manufacturers, and 26% collaborative presentations from both manufacturers and suppliers. All the presentations from SW Test 2012 as well as previous workshops (1993 to 2012) are available at the SW Test website (<http://www.swtest.org>).

The committee recognized the best podium presentations and Rey Rincon (Technical Program Chair) awarded the authors, including Best Presentation: *Full Wafer Contact Breakthrough with Ultra-High Pin Count* by Daisuke Takano and Takashi Naito (Advantest – Japan) and Tsutomu Shoji (Japan Electronic Materials, Corp. – Japan)

During the SW Test Tech EXPO, 37 full size exhibits showcased products from the wafer sort industry and the associated critical infrastructure. The international exhibitors from the US, Europe, and Asia represented key probe card vendors, major prober equipment manufacturers, probe card analyzer and probe process metrology companies, companies specializing in probe card cleaning, micro-pogo spring pin suppliers, and a variety of other probe related service providers.

SW Test 2012 also had four Platinum Supporters - International Test Solutions, FormFactor, Inc. (FFI), JEM America, Micronics Japan (MJC); four Gold Supporters – MultiTest, Teradyne, Rudolph Technologies, T.I.P.S. Messtechnik; and one Silver Supporter – Advanced Probing Systems, Inc. All corporate supporters participated in the 1st Annual SW Test Golf Scramble and for SW Test 2013, the 2nd Annual Scramble will be open to both supporters and exhibitors.

Plans are already underway for the 23rd Annual IEEE SW Test Workshop and Tech EXPO which will be held on June 9–12, 2013 at the Rancho Bernardo Inn, San Diego, CA (<http://www.ranchobernardoinn.com>). Abstract submission for the technical program and exhibitor registration for the Tech EXPO are already open!

62nd Electronic Components and Technology Conference (ECTC): Another Great Year!

The 62nd Electronic Components and Technology Conference held this year from May 29–June 1 at the Sheraton San Diego Hotel & Marina in San Diego, CA, USA, was one of the most successful in the long history of ECTC. Widely considered to be the premier global conference for electronic packaging and interconnect technologies, this year's technical program featured 36 oral presentation sessions, 4 interactive presentation sessions, 1 student poster session, 16 professional development courses, a special Tuesday technical session, and 3 evening panel and plenary sessions. In addition to daily luncheons, nightly receptions, a raffle drawing, and 81 exhibitors, the 62nd ECTC provided a multitude of options for technical engagement, networking, and business development.

Based on the increased number of attendees this year, the semiconductor packaging industry continued to show it is in a growth mode. 1234 attendees participated in ECTC this year, an increase of ~200 over last year's attendance. 589 abstracts were submitted for this year's conference from authors in 25 U.S. states and 26 countries, reflecting ECTC's global reach. 49% of the submitted abstracts were from universities and educational institutions, 40% were from corporations, and 11% from research institutes. 347 of these abstracts were accepted for presentation in oral, interactive presentation, and student poster sessions, reflecting a total acceptance rate of 59%. Once again this year, the Executive Committee formed a 3D/TSV workgroup to coordinate the 9 sessions dedicated to this important technology area. Rozalia Beica of Lam Research led the workgroup comprised of members from all of the technical subcommittees to create topically-focused sessions on interposers, TSV fabrication, and design, modeling, and characterization of 3D systems. For the first time, ECTC's poster sessions were renamed as Interactive Presentations, reflecting the importance of the one-on-one interaction with authors that these presentations provide. The 4 Interactive Presentation sessions also featured large video screens displaying quad chart summaries that provided at-a-glance information about the author's work. Once again, the technical subcommittees did an outstanding job in creating the technical program for ECTC, and their tireless efforts are very much appreciated!

On Tuesday, ECTC's Professional Development Courses were held, with 206 attendees participating in the 16 courses with topics ranging from 3D packaging and WLCSP to modeling and design.

Participants in Professional Development Courses were eligible for Continuing Education Units at no additional cost. The courses were organized by the PDC Committee chaired by Kitty Pearsall of IBM.

The International Electronics Manufacturing Initiative (iNEMI) held their North American Workshop at ECTC this year. This meeting, intended to solicit input for the 2013 iNEMI Roadmap, was open to all conference attendees.

The special technical session chaired by Raj Pendse of STATS ChipPAC on "Next Generation Packaging and Integration – The Transformed Role of the Packaging Foundry" drew a large audience to hear representatives from several major outsourced assembly and test companies (OSATs) to discuss the changes and challenges ahead for the packaging industry. Bob Lanzone (Amkor), Bill Chen (ASE), Mike Ma (SPIL), Steve Anderson (STATS ChipPAC), and Dan Tracy (SEMI) were the speakers.

Tuesday evening, students were invited to participate in the annual ECTC Student Reception, hosted by Eric Perfecto of IBM. Students had the opportunity to interact with technical subcommittee chairs to learn about the abstract selection process and network with industry professionals. Session chairs and speakers attended the General Chair's Reception to welcome them to ECTC.

Capping off the opening evening, Rolf Aschenbrenner of Fraunhofer IZM and Ricky Lee of the Hong Kong University of Science and Technology co-chaired the ECTC Panel Session on "Power Electronics – A Booming Market". Dan Kinzer (Fairchild Semiconductor), Klaus-Dieter Lang (Fraunhofer IZM), Lionel Cadix (Yole Development), Ljubisa Stevanovic (GE Global Research), and Bernd Roemer (Infineon Technologies) were the invited speakers.

Technical sessions began on Wednesday, starting at 8AM each day with 6 parallel sessions running each morning and afternoon. Each day started with a Speaker's Breakfast where session chairs and speakers gathered for a welcome message from ECTC Program Chair Senol Pekin of Intel.

3D technologies proved to be the hot topic again this year. Up to 200 attendees packed the conference halls to hear about the latest developments in 3D bonding and assembly, interposer technology, and TSV manufacturing. Flip chip and wafer level packaging sessions also continued to draw many attendees. Sessions on package reliability, solder and material characterization, innovative testing, and optoelectronics were also popular and illustrate the breadth of technologies that were presented this year.



The 62nd ECTC Executive Committee



General Chair David McCann welcomes speakers and session chairs at the General Chair's Reception



The Technology Corner located in the Pavilion tent provided plenty of room for attendees



Plenty of food and conversation during the Gala Reception

Gregg Bartlett of GLOBALFOUNDRIES was Wednesday's ECTC Luncheon keynote speaker, where he spoke about emerging 2.5D and 3D technologies, how they are bridging the gap between silicon foundries and the packaging world, and the emergence of a new supply chain model requiring closer collaboration between foundries, OSATs, and customers. The 2011 ECTC best paper awards were also presented.

Wednesday evening's events began with the Exhibitor Reception held in the Technology Corner exhibit. This year's Technology Corner consisted of 81 exhibitors, by far the most ever at ECTC, and the larger outdoor pavilion tent was the ideal setting for networking and for exhibitors to present the most recent advances in services, equipment, and materials.

That night's ECTC Plenary Session, "Photonics: Expanding Markets & Emerging Technologies", was chaired by Chris Bower of Semprius. Speakers Ashok Krishamoorthy (Oracle), Jeff Perkins (Yole Development), Sheng Liu (Huazhong Univ. of Science and Tech.), Alexander Fang (Aurrion), Timo Aalto (VTT), and Frank Libsch (IBM) discussed photonics markets, applications, and technologies and the growing impact photonics will have on microsystems.

CPMT sponsored the Thursday luncheon where the Society presented its 2012 awards. Mauro Walker was honored with the 2012 CPMT Award for his many contributions in advancing electronic

manufacturing while at Motorola. Longtime IEEE and CPMT volunteer Paul Wesling was honored for over 35 years of service with the IEEE CPMT Regional Contributions Award.

The 63rd ECTC planning meeting was held Thursday afternoon, chaired by Beth Keser of Qualcomm who will serve as the Program Chair for next year's ECTC. Beth detailed the 62nd ECTC statistics and presented the timeline for the 63rd ECTC which will be held at the Cosmopolitan Hotel in Las Vegas, NV, USA from May 28–May 31, 2013. CPMT Representative C.P. Wong introduced Alan Huffman of RTI International as the Assistant Program Chair for the 63rd ECTC.

Thursday evening's Gala Reception was held outside on the Bayview Lawn, overlooking Coronado Island and the San Diego Bay. Attendees and volunteers enjoyed great food, great weather, and great conversation with friends and colleagues while sailboats passed by. General Chair David McCann thanked attendees, exhibitors, sponsors, and volunteers for helping to make the 62nd ECTC one of the most successful conferences to date.

Thursday night was the CPMT Seminar, "Advanced Coreless Package Substrate & Material Technologies", co-chaired by Kishio Yokouchi of Fujitsu Interconnect Technologies and Venky Sundaram of Georgia Tech and invited speakers Yuji Nishitani (Sony), Tanaka Kuniyuki (Shinko Electric Industries), Takeshi Eriguchi (Asahi Glass), and Masateru Koide (Fujitsu Advanced Technologies).

Although Friday was the last day of the conference, both morning and afternoon sessions were very well attended, a testament to the strength of the technical program from beginning to end. The Friday ECTC Program Chair's luncheon was a fun-filled event, as always, with ECTC Treasurer Tom Reynolds overseeing the annual raffle drawing where many prizes were given out including an Xbox with Kinect and a free registration to next year's ECTC. C.P. Wong awarded David McCann the General Chair award in recognition of his leadership of the 62nd ECTC.

The first Call for Papers for the 63rd ECTC and a link to ECTC's Flickr site are now available at www.ectc.net. This year's abstract deadline is October 8, 2012. In addition to abstracts for papers, proposals are also welcomed from those interested in teaching professional development courses. We look forward to seeing you next year in Las Vegas for the 63rd ECTC!



ECTC Plenary Session Chair Chris Bower (left) and invited speakers

CALL FOR PAPERS

EMPC2013 GRENOBLE, France 9-12 SEPTEMBER 2013



EMPC 2013 (European Microelectronics Packaging Conference) is the premier international conference organized by IMAPS-Europe and IEEE-CPMT. The program will focus on industrial needs and trends and on academic longer term solutions; This event brings together researchers, innovators, technologists, business and marketing managers with an interest in semiconductor packaging

Call for papers and conference topics:

EMPC 2013 explores a wide range of semiconductor packaging topics. The technical committee invites you to submit your recent developments, results for oral or poster presentation in the field of :

- Advanced packaging: 3D packaging, TSVs, interposers, wafer level packaging, fan-out WLP and embedded IC package, substrates (flexible, ceramic, laminates), PCB.
- CAD and tools for IO placement for advanced packaging, design for reliability, IC and package co-design, opto & RF package design, thermal & mechanical modeling & simulation,
- MEMS and smart system packaging,
- Innovative packaging for emerging and growing applications: photovoltaic, textile electronics medical, power, LEDs, photonics, optoelectronics...
- Materials, equipment and processes,
- Emerging technologies and novel approaches; microfluidics, carbon nano tubes, ...
- Assembly manufacturing and business aspects of the industry,
- Reliability, test & characterization, electromigration, thermal management
- Advanced interconnections: flip-chip, interconnections for advanced CMOS process nodes, WLP metallurgies, bumping techniques, non-traditional interconnections, PCB solutions.

The deadline for submitting abstracts is **15th February 2013.**

You are invited to submit abstracts of 250 words to one page max. (no figures, no tables, no formulas) that provide original previously unpublished, non-confidential and non commercial information.

Please click on [https:// www.conftool.com/empc2013/](https://www.conftool.com/empc2013/) to set up an account and upload your papers, or contact conference@empc2013.com with any queries.

- Your submission must include your mailing address, business telephone number and email address.
- Authors will be notified of paper acceptance with instruction for publication before **28th March 2013.**
- Authors will be invited to submit a paper (no format) for proceeding publication (2 to 6 pages) before **15th June 2013.**
- Upon recommendation of the program committee, submitted abstracts may be considered for poster presentation.
- Presentation conforming to the IMAPS template are due **20th August 2013.**

Short Courses / Tutorials

Proposals are solicited from professionals to give 3-hour tutorials. Each selected tutorial will be given a honorarium of 500 €. The topics should be relevant with the call of papers.

Best presentation award and best poster award:

The program committee will select the best paper presentation. The awarded co-authors will receive a personalized IMAPS award.

IEEE CPMT France Chapter Best poster award: Co-authors will share an award for the best poster as selected by the program committee.

Organized by



Co-organizers



IEEE



IEEE COMPONENTS, PACKAGING AND MANUFACTURING TECHNOLOGY SOCIETY



leti

Media sponsors



YOLE DÉVELOPPEMENT

I-Micronews



CALL FOR PAPERS

15th IEEE International Symposium and Exhibition on *Advanced Packaging Materials*

Time: February 27 to March 1, 2013

Location: Atrium Hotel, Irvine, California, USA

Sponsor: IEEE Components, Packaging and Manufacturing Technology (CPMT) Society

Abstracts are solicited in the following topical areas:

Adhesives and underfills

- materials & applications, advanced processes, and reliability

Circuit boards, substrates, and dielectrics

- advanced circuit boards and substrates, properties, and processing

Encapsulants, thin films, and coatings

- materials & applications, new processes, and reliability

Flip-chip interconnect materials and processing

- bumping materials, bumping methods, and reliability evaluations

Manufacturing and Reliability

- New manufacturing techniques and testing

Materials and processes for 3-D integration

- thru-silicon-via formation, stacking, plating and bonding

Optoelectronic and microwave materials

- New materials and processes for optoelectronic and microwave packaging

Solders and soldering operations

- lead-free solders, new bonding and soldering processes, reliability

Posters

Who should attend:

Attendees of this symposium have been researchers, developers, producers and users of materials and processes for packaging the whole range of electronic and optoelectronic products.

Abstract submission:

For presenting a paper in this symposium, please send an abstract (~ 150 words) via e-mail to cclee@uci.edu and copy myim@broadcom.com. Please include your affiliation, mailing address, phone number, and e-mail address in your submission.

Important dates:

Abstract submission deadline: December 15, 2012.

Acceptance notice: within 4 weeks of abstract receipt or Dec 31, 2012, whichever is earlier.

Full manuscript submission deadline: January 15, 2013

For more information, please contact:

General Chair: Tom Gregorich, Broadcom, Irvine, California, tomg@broadcom.com

Program Chair: Chin C. Lee, University of California, Irvine, California, cclee@uci.edu

Publicity Chair: Sam Karikalan, Broadcom, Irvine, California, samk@broadcom.com



17th IEEE Workshop on Signal and Power Integrity

May 12-15, 2013 – Paris, France Hotel Concorde La Fayette



CALL FOR PAPERS

Paper submissions due by January 31, 2013

www.spi2013.org

Workshop Chairman

José Schutt-Ainé
University of Illinois, Urbana
jesa@illinois.edu

Program Chair

Frédéric Broydé
Excem, France
fredbroyde@eurexcm.com

Secretariat

Karen Kuhns
University of Illinois, Urbana
Tel: (217) 333-1200
kuhns@illinois.edu

Organizing Committee

Kemal Aygun, Intel
Kaustav Banerjee, UCSB
Sonia Ben Dhia, INSA
Moises Cases, The Cases Group
Weng Cho Chew, UIUC
Evelyne Clavelier, Excem
Naresh Shanbhag, UIUC
Roberto Suaya, Mentor Graphics

Over the past sixteen years, this workshop has evolved into a forum of exchange on the latest research and developments on innovative schemes for signal and power integrity, and in the field of interconnect modeling, simulation and measurement at chip board and package levels. The workshop is also meant to bring together developers and researchers from industry and academia in order to encourage cooperation.

In view of last year's success, the Committee is looking forward to the 17th Edition which will convene at the Hotel Concorde La Fayette in Paris, France. The symposium will include both oral and poster sessions. A number of prominent experts will be giving tutorials on areas of emerging interest.

TOPICS

- Innovative schemes for SI and PI
- Noise reduction techniques
- High-speed link design and modeling
- Power distribution networks
- Electronic packages and microsystems
- 3D technologies for IC and packages
- RF, microwave mixed signal packaging
- Nano-interconnects and nano structures
- Electromagnetic theory and modeling
- Transmission line theory and modeling
- Macro-modeling, reduced order models
- Simulation tools for signal and power integrity
- Electromagnetic Compatibility
- Design methodology/flow
- Time and frequency-domain measurements
- Jitter and noise modeling
- Chip-package co-design
- Novel CAD concepts

Workshop Standing Committee

- Uwe Arz, Physikalisch-Technische Bundesanstalt, Braunschweig (GER)
- Flavio G. Canavero, Politecnico di Torino, Torino (ITA)
- Hartmut Grabinski, Leibniz University, Hannover (GER)
- Antonio Maffucci, University of Cassino, Cassino, (ITA)
- Michel S. Nakhla, Carleton University, Ottawa (CAN)
- José E. Schutt-Ainé, University of Illinois, Urbana (USA)
- Madhavan Swaminathan, Georgia Institute of Technology, Atlanta (USA)



59th IEEE HOLM Conference on Electrical Contacts - Call for Papers

22-25 September 2013

Hotel Viking, Newport, Rhode Island, USA

Prospective authors should submit a brief abstract (200 words maximum) online before January 20, 2013. Authors will be notified concerning acceptance of abstracts in late February 2013. Please include complete contact information for all correspondence to be sent.

Abstracts are to be submitted through the IEEE Conference eXpress website:

<http://www.ieee.org/conferencepublishing>

Enter Conference ID – holm13

SPECIFIC TECHNICAL AREAS

AUTOMOTIVE CONTACTS AND SENSORS

Hybrid Power, Lead Free, Hot Plugging, Series Arc Faults, Environmental Effects, Electroplating

COMMUNICATIONS

High frequency, Telecommunications, High-Speed Data Degradation Effects

POWER

Crimp Terminals, Lubricants, Busbar, Glowing Contacts

CONTACT MATERIALS

Air and Vacuum, High Frequency Relays, Ultra Miniature Relays, Reed Relays, Material Development, AgCdO, AgSnO₂, Sliding Contacts, Fretting, Thermal Analysis, Air and Vacuum Materials, Carbon Fiber,

DEGRADATION MECHANISMS

Switching Performance, Welding, Lubrication, Environmental Effects, Reliability and Diagnostics

ARC INTERRUPTION

Circuit Breakers, Hybrid Switches, Micro-Arcing, Contactors, Vacuum Interrupters, High Speed Film/Video, Superconducting Limiters

MODELING

3D FEA, Arc Motion, Dielectric Breakdown, Dynamic Welding

NEW TECHNOLOGY

MEM, Micro-Electro-Mechanical Switches & Relays, Nano-technology in connections, RF connectors, Superconductor connections, Arc Fault Safety, High DC Voltage Switching

IMPORTANT DATES

20 January 2013

26 February, 2013

22 June, 2013

22 September, 2013

Abstract Deadline

Notification of Acceptance

Completed Paper Deadline

Conference Begins

For additional information go to the Holm Website:

www.ewh.ieee.org/soc/cpmt/tc1/

EDAPS 2013

2013 IEEE Electrical Design of Advanced Packaging & Systems Symposium

December 12-14 & 15, 2013. Nara, Japan

Preliminary Announcement

First Call for Papers

Information for Authors

The IEEE Electrical Design of Advanced Packaging & Systems (EDAPS) symposium has been one of the most important events in Asia Pacific region for the researchers and developers related to the electrical design issues on chip, package and system levels. The EDAPS symposium consists of paper presentations, industry exhibitions, workshops and tutorials. The 2013 EDAPS will be held in Nara of Japan from December 12 to 14, 2013. Additionally, a special joint workshop with EMC Compo2013 will be embedded on Dec. 15th. The technical program of the symposium not only addresses the current technical issues but also brings out the challenges facing IC design, SiP/SoP packaging, EMI/EMC, and EDA tools and most importantly the challenge issues in advanced 3-D IC and packaging design. The symposium provides a major platform for researchers, designers and developers from diverse fields to exchange knowledge and build up network and community.

Paper Topics of Interest

- Signal Integrity
- Substrate Technology for Package and PCB
- Power Integrity / Ground Noise
- Time/Frequency Domain Measurement Techniques
- 3DIC / 3D-Stacked IC
- SiP/SoP
- Embedded Passives
- Electromagnetic Compatibility (EMC)
- Design and Modeling for High-speed Channels and Interconnects
- Package Reliability
- RF/Microwave Package
- Advanced Simulation Tools and CAD
- Testing on 3DIC and SiP
- Others

Important Dates

Deadline for Regular Paper Submission: June 25, 2013

Tutorial, Workshop, and Special Session

Proposal Submission: June 25, 2013

Acceptance Notice: August, 2013



IEEE



IEEE COMPONENTS, PACKAGING AND
MANUFACTURING TECHNOLOGY SOCIETY



Organized by Shizuoka University

See web site for more details

<http://www.edaps2013.org>

ASMC

May 14–16, 2013



ASMC 2013 SEMI Advanced Semiconductor Manufacturing Conference □ Saratoga Springs, New York



[AGENDA](#)

[REGISTER](#)

[TRAVEL](#)

[SPONSORSHIP](#)

[CONTACT US](#)

The 24th Annual SEMI Advanced Semiconductor Manufacturing Conference (ASMC 2013) [call for papers](#) is officially open. ASMC 2013 soliciting abstracts from professionals involved in all areas of semiconductor manufacturing. In addition to publication in the conference proceedings, select papers will be invited to participate in a special section on ASMC 2013 to be featured in the IEEE Transactions on Semiconductor Manufacturing. The conference will take place in Saratoga Springs, New York.

Papers co-authored between device manufacturers, equipment or materials suppliers, and/or academic institutions that demonstrate innovative, practical solutions for advancing semiconductor manufacturing are highly encouraged. Original, non-commercial and non-published works are being solicited in specific categories. Presentations on original, non-commercial and non-published works will be solicited in the [following areas](#):

- AM: Advanced Metrology
- AEPM: Advanced Equipment Processes and Materials
- AP/DFM: Advanced Patterning / Design for Manufacturability.
- APC: Advanced Process Control
- CFM: Contamination Free Manufacturing
- DM: Data Management and Data Mining Tools
- DI: Defect Inspection and Reduction
- ET/ID: Enabling Technologies and Innovative Devices
- ER: Equipment Reliability and Productivity Enhancements
- FA: Factory Automation
- GF: Green Factory
- IE: Industrial Engineering
- LM: Lean Manufacturing
- 3D/TSV: Packaging and Through Silicon Via
- YE: Yield Enhancement/Learning
- YM: Yield Methodologies

Best Paper Awards

ASMC 2012 Entegris Best Paper will be announced in October 2012 and presented at ASMC 2013.

ASMC 2012 GLOBALFOUNDRIES Best Student Paper will be announced in October 2012 and presented at ASMC 2013.

Who Attends ASMC?

- IC Manufacturers
- Equipment Manufacturers
- Materials Suppliers
- Chief Technology Officers
- Operations Managers
- Process Engineers
- Product Managers
- Academia

Author Instructions

Authors presenting a technical paper at ASMC 2013, please visit the [author instructions](#) for due dates, templates and additional information.

Abstract Submission

Sponsorships

Sponsorship opportunities for this event are available. Please contact Marlene Sibley at msibley@semi.org or 1.408.343.6988.

Technical Sponsors:



IEEE COMPONENTS, PACKAGING AND
MANUFACTURING TECHNOLOGY SOCIETY



Justify Your Attendance

Use the testimonial above and our [justification letter template](#) to show why your participation ASMC 2013, as an author or attendee, will benefit you and your organization.

ASMC Committee

SEMI thanks the ASMC committee members, who volunteer countless hours in support of our annual conference.

<http://www.semi.org/asmc2013>

Upcoming CPMT Society Sponsored and Cosponsored Conferences

- | | |
|--|--|
| Name: 2012 IEEE 14th Electronics Packaging Technology Conference - (EPTC) | Name: 2013 Symposium on Design, Test, Integration and Packaging of MEMS/MOEMS (DTIP) |
| Dates: December 5–7, 2012 | Dates: April 16–18, 2013 |
| Location: Singapore, Singapore | Location: Barcelona, Spain |
| URL: http://www.eptc-ieee.net/index.html | URL: http://cmp.imag.fr/conferences/dtip/dtip2013/index.php |
| Name: 2012 IEEE Electrical Design of Advanced Packaging and Systems Symposium (EDAPS) | Name: 2013 17th IEEE Workshop on Signal and Power Integrity (SPI) |
| Dates: December 9–11, 2012 | Abstract Submission Date: January 31, 2013 |
| Location: Taipei, Taiwan | Dates: May 12–15, 2013 |
| URL: http://edaps2012.ntu.edu.tw/ | Location: Paris, France |
| | URL: http://spi2013.ece.illinois.edu/ |
| Name: 2012 IEEE CPMT Symposium Japan (Formerly VLSI Packaging Workshop of Japan) | Name: 2013 24th Annual SEMI Advanced Semiconductor Manufacturing Conference (ASMC) |
| Dates: December 10–12, 2012 | Dates: May 14–16, 2013 |
| Location: Kyoto, Japan | Location: Saratoga Springs, NY, USA |
| URL: http://www.vlsi-pkg-ws.org/ | URL: http://www.semi.org/asmc2013 |
| Name: 2012 14th International Conference on Electronic Materials and Packaging (EMAP) | Name: 2013 IEEE 63rd Electronic Components and Technology Conference (ECTC) |
| Dates: December 13–16, 2012 | Dates: May 25–June 2, 2013 |
| Location: Lantau Island, Hong Kong | Location: Las Vegas, NV, USA |
| URL: http://ihome.ust.hk/~emap2012//index.html | URL: http://www.ectc.net |
| Name: 2013 IEEE 15th International Symposium and Exhibition on Advanced Packaging Materials (APM) | Name: 2013 IEEE Semiconductor Wafer Test Workshop (SWTW 2013) |
| Abstract Submission Date: December 15, 2012 | Abstract Submission Date: February 22, 2013 |
| Dates: February 27–March 1, 2013 | Dates: June 8–12, 2013 |
| Location: Irvine, CA USA | Location: San Diego, CA, USA |
| URL: http://www.apm2013.org/ | URL: http://www.swtest.org/ |
| Name: 2013 14th International Symposium on Quality Electronic Design (ISQED) | Name: 2013 35th Annual Electrical Overstress/Electrostatic Discharge Symposium (EOS/ESD) |
| Dates: March 4–6, 2013 | Dates: September 8–13, 2013 |
| Location: Santa Clara, CA, USA | Location: Las Vegas, NV, USA |
| URL: http://www.isqed.org/ | URL: http://www.esda.org |
| Name: 2013 IEEE/CPMT 29th Semiconductor Thermal Measurement & Management Symposium (SEMI-THERM) | Name: 2013 IMAPS-Europe European Microelectronics and Packaging Conference (EMPC) |
| Dates: March 17–21, 2013 | Dates: September 9–12, 2013 |
| Location: San Jose, CA, USA | Location: Grenoble, France |
| URL: http://www.semi-therm.org/ | URL: http://www.empc2013.com/ |
| Name: 2013 14th Thermal, Mechanical and Multiphysics Simulation and Experiments in Micro-Electronics and Micro-Systems Conference (EuroSimE) | Name: 2013 IEEE 59th Holm Conference on Electrical Contacts (Holm 2013) |
| Dates: April 14–17, 2013 | Abstract Submission Date: January 20, 2013 |
| Location: Wroclaw, Poland | Dates: September 22–25, 2013 |
| URL: http://www.eurosim.org/index.htm# | Location: Newport, RI, USA |
| | URL: http://www.ewh.ieee.org/soc/cpmt/tc1/h2013/h2013call.html |

Name: 2013 IEEE International 3D Systems Integration Conference (3DIC)	Name: 2014 IEEE 64th Electronic Components and Technology Conference (ECTC)
Dates: October 2–4, 2013	Abstract Submission Date: October 15, 2013
Location: San Francisco, CA, USA	Dates: May 23–31, 2014
URL: http://www.3dic-conf.org/	Location: Orlando, FL, USA
	URL: http://www.ectc.net
Name: 2013 IEEE 22nd Conference on Electrical Performance of Electronic Packaging and Systems (EPEPS)	Name: 2014 IEEE Semiconductor Wafer Test Workshop (SWTW 2014)
Dates: October 27–30, 2013	Abstract Submission Date: February 14, 2014
Location: San Jose, CA, USA	Dates: June 6–11, 2014
URL: http://epeps.ece.illinois.edu/	Location: San Diego, CA, USA
Name: 2013 IEEE Electrical Design of Advanced Packaging & Systems Symposium (EDAPS)	URL: http://www.swtest.org/
Abstract Submission Date: June 25, 2013	Name: 2014 5th Electronic System Integration Technology Conference (ESTC)
Dates: December 12–14, 2013	Dates: September 15–18, 2014
Location: Nara, Japan	Location: Helsinki, Finland
URL: http://www.edaps2013.org/	

On the Web.....at cpmt.ieee.org

Content for CPMT Society Members only (click on Members Only tab)

IEEE/CPMT Workshop: “Thin Is In: Thin Chip & Packaging Technologies as Enabler for Innovative Mobile Devices”

(July 2012 at SEMICON West 2012)

Electronic products, such as smart phones, tablets and other consumer products drive the overall trend of maximum functional integration in the smallest and thinnest package with lowest packaging costs. Here, thin 3D-packaging is one of the key Technologies to achieve these goals. Developments have lately been made with various embedding technologies, such as Fan out WLP and embedded devices. Higher integration levels and lower profiles are also achieved with wafer-level processes at which most R&D is concentrated in the commercialization of 2.5D IC's (with silicon interposer) & 3D ICs, as well as coreless substrate. Furthermore, there is tremendous pressure to decrease overall package height even with the additional dies stacking through innovation in wafer thinning, TSV, and ultrathin interconnects.

In this workshop, leaders from key segments of the eco-system shared their perspectives and experiences on the readiness for commercialization and what the future directions and opportunities in this emerging area of “Thin Packaging Technology.

- ***Thin is In: Packaging for Mobile Applications***, Steve Bezuk, Qualcomm CDMA Technologies
- ***The Thin Package Challenge Never Ends***, Bernd Appelt, ASE Group
- ***ChipletTTM and ChipsetTTM: A Fine Line Multilayer Flex Based Embedded Die Semiconductor Packaging Solution***, Ted Tessier, Flip Chip International LLC
- ***Coreless Substrate. Its Performance and Future Direction***, Mitsuharu Shimizu, Shinko
- ***Amkor's Thru Molded Via (TMV) Thin Package on Package Technology Roadmap***, Robert Lanzone, Amkor Technology

**IEEE Components, Packaging and Manufacturing
Technology Society**

Marsha Tickman, Executive Director
445 Hoes Lane
Piscataway, NJ 08854 USA

Getting the Most out of IEEE and CPMT Membership: eBooks

Did you know that IEEE members now have access to more than 220 eBooks from the IEEE Press collection through IEEE Xplore, including: handbooks; introductory and advanced texts; reference works; professional books.

Follow 3 simple steps:

1. Log in to IEEE Xplore <http://www.ieeexplore.ieee.org/Xplore/guesthome.jsp> using your IEEE Member Web account.
2. Under the “Browse” heading in the left-hand navigation, click on “Books”.
3. Select the “Classics” tab from the top of the page. Under this tab you will find a listing of all the Free titles.

Here are a few examples of available books in pdf format: (more added every year)

1. *Lead-Free Electronics: iNEMI Projects Lead to Successful Manufacturing* by E. Bradley, C. Handwerker, J. Bath, R. Parker and R. Gedney; Publication Date: 2007
2. *Magnetic Actuators and Sensors* by J. Brauer; Publication Date: 2006
3. *Multigrid Finite Element Methods for Electromagnetic Field Modeling* by Y. Zhu and A. Cangellaris; Publication Date: 2006
4. *Silicon Germanium: Technology, Modeling, and Design* by R. Singh, H. Oprysko and D. Hamee; Publication Date: 2004
5. *Integrated Passive Component Technology* by R. Ulrich and L. Schaper; Publication Date: 2010

For more information visit: http://www.ieee.org/membership_services/membership/products/ebookclassics.html